

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
1	BRS	L1	520	((thin adj film adj stack)or film) near8 MEMS	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:15	
2	BRS	L2	2335	359/290-298.CCLS.	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:15	
3	BRS	L3	23	1 AND 2	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:18	
4	BRS	L4	2954	430/319,320,321.ccls.	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:18	
5	BRS	L5	3	1 and 4	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:18	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
6	BRS	L6	33040	427/162-248.1.ccls.	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:19	
7	BRS	L7	8	1 and 6	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:20	
8	BRS	L8	14678	((microelectromechanical adj system) or MEMS)	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:21	
9	BRS	L9	15114 7	etch\$3 and pattern\$3 and deposit\$3	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:22	
10	BRS	L10	4598	8 and 9	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:29	

	Type	L #	Hits	Search Text	DBs	Time Stamp	Comments
11	BRS	L11	9	10 and (metal) and (conductive adj oxide or oxide) and (fluoride) and (silicide) and polymer	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:31	
12	BRS	L12	901	216/2.ccls.	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:31	
13	BRS	L13	1	11 and 12	US- PGPUB ; USPAT ; EPO; JPO; DERWE NT	2005/01/1 1 16:31	